

Surface chemical analysis — Depth profiling — Measurement of sputtered depth

ICS 17.040.20; 71.040.40

National foreword

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According to the replies received by the end of the review period, the responsible BSI Committee will decide whether to support the conversion into an international standard. Comments should be sent in writing to the Secretary of BSI Technical Committee CII/60, Surface chemical analysis, at 389 Chiswick High Road, London W4 4AL, giving the document reference and clause number and proposing, where possible, an appropriate revision of the text.

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Cross-references

The British Standards which implement international or European publications referred to in this document may be found in the BSI Standards Catalogue under the section entitled “International Standards Correspondence Index”, or by using the “Find” facility of the BSI Standards Electronic Catalogue.

Summary of pages

This document comprises a front cover, an inside front cover, the ISO/TR title page, pages ii to v, a blank page, pages 1 to 12, an inside back cover and a back cover.

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TECHNICAL REPORT

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Surface chemical analysis — Depth profiling — Measurement of sputtered depth

*Analyse chimique des surfaces — Profilage d'épaisseur — Mesurage de
l'épaisseur bombardée*



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Foreword

ISO (the International Organization for Standardization) is a worldwide federation of national standards bodies (ISO member bodies). The work of preparing International Standards is normally carried out through ISO technical committees. Each member body interested in a subject for which a technical committee has been established has the right to be represented on that committee. International organizations, governmental and non-governmental, in liaison with ISO, also take part in the work. ISO collaborates closely with the International Electrotechnical Commission (IEC) on all matters of electrotechnical standardization.

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In exceptional circumstances, when a technical committee has collected data of a different kind from that which is normally published as an International Standard ("state of the art", for example), it may decide by a simple majority vote of its participating members to publish a Technical Report. A Technical Report is entirely informative in nature and does not have to be reviewed until the data it provides are considered to be no longer valid or useful.

Attention is drawn to the possibility that some of the elements of this Technical Report may be the subject of patent rights. ISO shall not be held responsible for identifying any or all such patent rights.

ISO/TR 15969 was prepared by Technical Committee ISO/TC 201, *Surface chemical analysis*, Subcommittee SC 4, *Depth profiling*.

Introduction

This Technical Report is intended to be used as follows:

- a) For the determination of the depth scale in sputter depth profiling where signal intensity is obtained as a function of sputtering time (or ion dose density). The sputtered depth per sputtering time is the sputtering rate (typically reported in nm/s).
- b) To enhance the comparability of depth profiling data obtained with different instruments and to increase the reliability and use of depth profiling in industrial applications.
- c) To serve as the basis for the development of International Standards on the measurement of sputtered depth.